

METHODS AND APPARATUS FOR RAPIDLY COOLING A SUBSTRATE

FIELD

[0001] Embodiments of the present disclosure generally relate to substrate processing equipment.

BACKGROUND

[0002] Formation of some devices on substrates requires multiple processes in various chambers. For example, processes such as atomic layer deposition (ALD), physical vapor deposition (PVD), chemical vapor deposition (CVD), etching, etc., may be performed to form or remove layers on a substrate. Many of these processes require the substrate to be heated to a high temperature and, therefore, subsequent cooling of the processed substrate is necessary.

[0003] Some processes require a cool down step before further process steps can be performed. The inventors have observed that many conventional cool down stations are operated in a high vacuum environment and, therefore, take a long period of time to cool a substrate. As such, these cooling stations are a bottleneck in a substrate transfer process in which the substrate is moved from one chamber to another.

[0004] Therefore, the inventors have provided improved cooling chambers for more rapidly cooling a substrate.

SUMMARY

[0005] Embodiments of methods and apparatus for rapidly cooling a substrate are provided herein. In some embodiments, a cooling chamber for cooling a substrate includes a chamber body having an inner volume; a substrate support disposed in the chamber and having a support surface to support a substrate; a plate disposed in the chamber body opposite the substrate support, wherein the substrate support and the plate are movable with respect to each other between a first position and a second position, wherein when in the first position the substrate support and the plate are disposed away from each other such that the support surface is exposed to a first volume within the inner volume, wherein when in the second position the substrate support and the plate are disposed adjacent to each other such that the

support surface is exposed to a second volume within the inner volume, and wherein the second volume is smaller than the first volume; a plurality of flow channels disposed in one or more of the plate or the substrate support to flow a coolant; and a gas inlet to provide a gas into the second volume.

[0006] In some embodiments, a substrate processing system includes a central vacuum transfer chamber; at least one vacuum processing chamber coupled to the central vacuum transfer to perform a process on a substrate; and at least one cooling chamber coupled to the central vacuum transfer chamber to cool the substrate. The cooling chamber may include a chamber body having an inner volume; a substrate support disposed in the chamber and having a support surface to support a substrate; a plate disposed in the chamber body opposite the substrate support, wherein the substrate support and the plate are movable with respect to each other between a first position and a second position, wherein when in the first position the substrate support and the plate are disposed away from each other such that the support surface is exposed to a first volume within the inner volume, wherein when in the second position the substrate support and the plate are disposed adjacent to each other such that the support surface is exposed to a second volume within the inner volume, and wherein the second volume is smaller than the first volume; a plurality of flow channels disposed in one or more of the plate or the substrate support to flow a coolant; and a gas inlet to provide a gas into the second volume.

[0007] In some embodiments a method for cooling a substrate includes placing a substrate onto a support surface of a substrate support disposed within an inner volume of a cooling chamber; moving at least one of the substrate support or a plate disposed in the cooling chamber opposite the substrate support from a first position, in which the substrate is placed onto the support surface, to a second position, in which a second volume is created between the support surface and the plate, the second volume being smaller than and substantially sealed off from a remaining portion of the inner volume; flowing a gas into the second volume to increase a pressure within the second volume; and flowing a coolant through a plurality of channels disposed in at least one of the substrate support or the plate to cool the substrate.

[0008] Other and further embodiments of the present disclosure are described below.

BRIEF DESCRIPTION OF THE DRAWINGS

[0009] Embodiments of the present disclosure, briefly summarized above and discussed in greater detail below, can be understood by reference to the illustrative embodiments of the disclosure depicted in the appended drawings. However, the appended drawings illustrate only typical embodiments of the disclosure and are therefore not to be considered limiting of scope, for the disclosure may admit to other equally effective embodiments.

[0010] Figure 1 depicts a processing system suitable for use with the inventive cooling chamber in accordance with some embodiments of the present disclosure.

[0011] Figure 2 depicts a cooling chamber in accordance with some embodiments of the present disclosure.

[0012] Figure 3 depicts a partial view of the inventive cooling chamber in accordance with some embodiments of the present disclosure.

[0013] Figures 4 depicts a partial view of the inventive cooling chamber in accordance with some embodiments of the present disclosure.

[0014] Figure 5 depicts a top of a substrate support suitable for use with the inventive cooling chamber in accordance with some embodiments of the present disclosure.

[0015] Figure 6 depicts a flow diagram illustrating a method for cooling a substrate in accordance with some embodiments of the present disclosure.

[0016] To facilitate understanding, identical reference numerals have been used, where possible, to designate identical elements that are common to the figures. The figures are not drawn to scale and may be simplified for clarity. Elements and features of one embodiment may be beneficially incorporated in other embodiments without further recitation.

DETAILED DESCRIPTION

[0017] Embodiments of methods and apparatus for rapidly cooling a substrate are provided herein. Embodiments of the inventive cooling chamber may advantageously increase throughput by decreasing the amount of time necessary to cool a substrate. Embodiments of the inventive processing chamber may be easily retrofitted to existing processing systems, advantageously avoiding unnecessary and costly modification of existing processing systems.

[0018] Figure 1 is a schematic top-view diagram of an exemplary multi-chamber processing system 100 that may be suitable for use with the present inventive cooling chamber disclosed herein. Examples of suitable multi-chamber processing systems that may be suitably modified in accordance with the teachings provided herein include the ENDURA[®], CENTURA[®], and PRODUCER[®] processing systems or other suitable processing systems commercially available from Applied Materials, Inc., located in Santa Clara, California. Other processing systems (including those from other manufacturers) may be adapted to benefit from the embodiments disclosed in the present application.

[0019] In some embodiments, the multi-chamber processing system 100 may generally comprise a vacuum-tight processing platform 102, a factory interface 104, and a system controller 140. The processing platform 102 may include a plurality of process chambers 190A-D, at least one cooling chamber 195A-B (two shown in Figure 1) and at least one load-lock chamber (two shown) 184 that are coupled to a transfer chamber 188. A transfer robot 106 is centrally disposed in the transfer chamber 188 to transfer substrates between the load lock chambers 184, the process chambers 190A-D, and the at least one cooling chamber 195A-B. The process chambers 190A-D may be configured to perform various functions including layer deposition including atomic layer deposition (ALD), chemical vapor deposition (CVD), physical vapor deposition (PVD), etch, pre-clean, de-gas, orientation and center-finding, annealing, and other substrate processes. Each of the process chambers 190A-D may include a slit valve or other selectively sealable opening to selectively fluidly couple the respective inner volumes of the process chambers 190A-D to the inner volume of the transfer chamber 188. Similarly, each load lock

chamber 184 may include a port to selectively fluidly couple the respective inner volumes of the load lock chambers 184 to the inner volume of the transfer chamber 188.

[0020] The factory interface 104 is coupled to the transfer chamber 188 via the load lock chambers 184. In some embodiments, each of the load lock chambers 184 may include a first port 123 coupled to the factory interface 104 and a second port 125 coupled to the transfer chamber 188. The load lock chambers 184 may be coupled to a pressure control system which pumps down and vents the load lock chambers 184 to facilitate passing the substrate between the vacuum environment of the transfer chamber 188 and the substantially ambient (*e.g.*, atmospheric) environment of the factory interface 104.

[0021] In some embodiments, the factory interface 104 comprises at least one docking station 183 and at least one factory interface robot 185 (one shown) to facilitate transfer of substrates from the factory interface 104 to the processing platform 102 for processing through the load lock chambers 184. The docking station 183 is configured to accept one or more (four shown) front opening unified pods (FOUPs) 187A-D. Optionally, one or more metrology stations (not shown) may be coupled to the factory interface 104 to facilitate measurement of the substrate from the FOUPs 187A-D. A substrate treatment apparatus 195 may also be coupled to the factory interface 104 to enable treatment of the substrates before they are moved to the load lock chambers 184. The factory interface robot 185 disposed in the factory interface 104 is capable of linear and rotational movement (arrows 182) to shuttle cassettes of substrates between the load lock chambers 184 and the one or more FOUPs 187A-D. Because current cooling apparatuses are in the same vacuum environment as the rest of the processing platform, the time to cool a substrate is adversely affected. The inventors have designed a cooling chamber, which, although disposed in the processing platform at vacuum, can cool the substrate in an environment with a higher pressure, advantageously reducing the time required to cool the substrate.

[0022] Figure 2 depicts a cooling chamber 200 according to some embodiments of the present disclosure. The cooling chamber 200 may be used in the multi-chamber

processing system 100 described above, or in other multi-chamber processing systems. The cooling chamber 200 generally comprises a chamber body 202 defining an inner volume 204, a substrate support 208 disposed within the inner volume 204, and a plate 214 disposed opposite the substrate support.

[0023] The substrate support 208 includes a support surface 210 to support a substrate 212 during cooling. The substrate 212 may rest directly upon the support surface or on other support elements. For example, as depicted in Figure 5, in some embodiments, a plurality of support elements 506 may be provided to support the substrate 212 in a spaced apart relation to the support surface 210 to minimize potential contamination of the substrate 212 through contact with the substrate support 208. The plurality of support elements 506 may be formed of any material whose properties prevent contamination (e.g., particle generation or undesirable material adhesion to the substrate) of the backside of the substrate 212. For example, in some embodiments, the plurality of support elements 506 are sapphire balls.

[0024] The plate 214 is disposed opposite the support surface 210 of the substrate support 208. In some embodiments, the plate 214 may be disposed in or proximate a lid or upper portion of the chamber body 202 (as shown in Figure 2). The substrate support 208 and the plate 214 are movable with respect to each other between a first position wherein the substrate support 208 and the plate 214 are disposed away from each other (e.g., as shown in Figure 2) and a second position wherein the substrate support 208 and the plate 214 are disposed adjacent to each other (e.g., as shown in Figure 3).

[0025] In the first position, the support surface 210 of the substrate support 208 is exposed to a first volume 206 within the inner volume 204. The first volume 206 is essentially the entire inner volume 204. For example, the first volume 206 may be predominantly bounded by the plate 214 and inner surfaces of the chamber body 202. In the second position, the support surface 210 is exposed to a second volume (second volume 306 shown in Figure 3) within the inner volume 204. The second volume 306 is smaller than the first volume 206. For example, the second volume 306 may be predominantly bounded by the plate 214 and the support surface 210 of

the substrate support 208. The second volume 306 may be orders of magnitude smaller than the first volume 206. For example, in some embodiments, the second volume 306 may be less than 10 percent, or less than five percent, or about 2 to about 3 percent of the first volume 206. In one non-limiting example, the first volume may be about 9 liters and the second volume may be about 0.25 liters.

[0026] In some embodiments, the plate 214 is fixed and the substrate support 208 may be coupled to a lift mechanism 226 to control the position of the substrate support 208 between the first position (e.g., a lower position as shown in Figure 2) and the second position (e.g., an upper position as shown in Figure 3). Alternatively or in combination, the plate 214 may be movable with respect to the substrate support 208. In the configuration shown in Figure 2, the first, or lower position is suitable for transferring substrates into and out of the chamber via an opening 222 disposed in a wall of the chamber body 202. The opening 222 may be selectively sealed via a slit valve 224, or other mechanism for selectively providing access to the interior of the chamber through the opening 222. The second, or upper position is suitable for more rapidly cooling the substrate.

[0027] A lift pin assembly 238 including a plurality of lift pins may be provided to raise the substrate 212 off of the support surface 210 to facilitate placement and removal of the substrate 212 onto and off of the substrate support 208. Figure 5 depicts a top view of a substrate support in accordance with embodiments of the present disclosure. As depicted in Figure 5, a plurality of lift pin holes 504 are shown extending through the substrate support 208 to facilitate movement of the lift pins of the lift pin assembly 238.

[0028] Returning to Figure 2, the cooling chamber 200 may include one or more mechanisms to enhance the rate of cooling of the substrate 212. In some embodiments, a gas supply 228 may be coupled to the cooling chamber 200 via a gas inlet to provide one or more gases to the inner volume 204. Although only one inlet is shown in Figure 2, additional or alternative gas inlets may be provided in the plate 214 or in other locations suitable to provide the one or more gases to the second volume 306. Examples of suitable gases for the one or more gases include

inert gases, such as argon (Ar), helium (He), nitrogen (N₂), or the like, or reducing gases, such as hydrogen (H₂) or the like, or combinations of these gases

[0029] Specifically, the gas supply 228 supplies gas to the second volume 306 when the substrate support 208 and the plate 214 are disposed adjacent to each other. Providing the one or more gases to the second volume advantageously facilitates raising the pressure within the second volume 306, which in turn enhances the rate of heat transfer from the substrate to surrounding components of the cooling chamber 200, such as the substrate support 208 and the plate 214. Moreover, by providing the one or more gases to the second volume 306, which is much smaller than the first volume 206 or the inner volume 204 of the cooling chamber 200, the pressure may be raised without significantly raising the pressure of the coolant chamber 200 as a whole, advantageously reducing the time that would be required to pressurize and depressurize the entire coolant chamber or to rely upon a slower rate of cooling of the substrate in the lower pressure environment.

[0030] In some embodiments, the gas inlet may be provided through the plate 214 to provide the one or more gases to the second volume 306. For example, as shown in greater detail in Figure 3, in some embodiments, the gas supply 228 may be coupled to the second volume 306 through a central opening 304 (e.g., a gas inlet) disposed through the plate 214. A cover 310 may be coupled to the plate 214 on a surface opposite the inner volume 204. The cover 310 is coupled to a conduit 314 that leads ultimately to the gas supply 228. A seal or gasket 312 may be disposed between the cover 310 and the plate 214 to minimize or prevent leakage of the one or more gases provided by the gas supply 228 during operation. Other configurations of providing the gas inlet in the plate 214 or other locations may also be used.

[0031] Returning to Figure 2, in some embodiments, an annular seal 236 may be disposed between the substrate support 208 and the plate 214 such that the annular seal 236 contacts the plate 214 when in the substrate support 208 and the plate 214 are in the second position. The annular seal surrounds the support surface 210 of the substrate support 208. The annular seal 236 serves to substantially seal off the

second volume defined between the plate 214 and the support surface 210 when the substrate support 208 is in the upper position. Thus, the annular seal 236 facilitates controlling the amount of isolation between the second volume 306 and the remaining portion of the inner volume 204 such that the one or more gases provided to the second volume 306 flow into the remaining portion of the inner volume at a low, controlled rate.

[0032] In some embodiments, the annular seal 236 is disposed in the substrate support 208. In some embodiments, the substrate support 208 may include an outer ring 232 surrounding the support surface 210. The outer ring 232 includes an annular groove 234 which retains the annular seal 236. For example, as illustrated in Figure 3, when the substrate support 208 is in the second position, the annular seal 236 substantially seals the second volume 306 from the remaining portion of the inner volume 204 of the cooling chamber 200.

[0033] In some embodiments, a second annular seal 302 may be disposed between the outer ring 232 and the substrate support 205 to ensure that the pressurized one or more gases in the second volume 306 do not flow into the remaining portion of the inner volume 204 from beneath the outer ring 232. For example, the second annular seal 302 may be disposed in a second annular groove 308 in a bottom surface of the outer ring 232. Alternatively, the second annular seal 302 may be disposed partially or completely within a groove formed in the substrate support 208.

[0034] Figure 4 depicts a close-up of area around the outer ring 232 while the substrate support is in the second position shown in Figure 3 to more clearly show features for controlling the flow of the one or more gases from the second volume 306 into the remaining portion of the inner volume 204. As illustrated in Figure 4, an annular channel 402 is disposed between the outer ring 232 and the substrate support 208. For example, the annular channel 402 may be defined between an inner diameter of a portion of the outer ring 232 adjacent the support surface 210 and an outer diameter of the support surface 210 of the substrate support 208. The annular channel 402 extends in a direction opposite the plate 214.

[0035] At least one through hole 404 may be disposed through the outer ring 232 from a peripheral surface of the outer ring 232 to the annular channel 402. The at least one through hole 404 and the annular channel 402 fluidly couple the second volume 306 to the remaining portion of the inner volume 204. For example, Figure 5 depicts a top view of a substrate support in accordance with embodiments of the present disclosure. As depicted in Figure 5, three through holes 404 are shown extending from the annular channel 402 to the peripheral edge of the outer ring 232. Although three through holes 404 are illustrated in Figure 5, any number of through holes (e.g., one or more) may be provided to control the flow of gas from the second volume 306 to the remaining portion of the inner volume 204.

[0036] Returning to Figure 4, in some embodiments, the annular channel 402 is substantially vertical and the at least one through hole 404 is substantially horizontal (e.g., the annular channel 402 and the at least one through hole 404 may be perpendicular to each other). The at least one through hole 404 may include an outer section 406 with a diameter larger than that of the through hole 404. The arrows depicted in Figure 4 illustrate a gas flow path according to some embodiments of the present disclosure wherein the inner volume 204 of the coolant chamber is maintained at a first pressure and the second volume 306 is maintained at a second pressure that is greater than the first pressure. As illustrated in Figure 4, the resultant flow path provides a choked flow of gas from the second volume 306 to the remaining portion of the inner volume 204.

[0037] Returning to Figure 2, in some embodiments, an inner volume facing surface of the plate 214 may be contoured to facilitate providing a smooth, laminar, and more uniform flow of gas within the second volume 306. For example, the surface of the plate 214 facing the second volume may be concave, to form a shallow bowl or funnel that provides a greater thickness across the second volume 306 near a central axis of the substrate support 208 (and the plate 214) and a lesser reducing thickness across the second volume 306 at positions radially outward of the central axis. In some embodiments, a thickness of the plate 214 increases outwardly from the central opening 304 to provide the concave shape of the second volume facing surface of the plate 214.

[0038] In some embodiments, at least one of the plate 214 or the substrate support 208 may include one or more flow channels to flow a coolant to increase the rate of cooling of the substrate 212. For example, as shown in Figure 2, the substrate support 208 may include one or more flow channels 218 disposed in the substrate support 208, for example, beneath the support surface 210. A coolant supply 216 may be coupled to the one or more flow channels 218 to supply a coolant to the flow channels 218. Alternatively or in combination, the plate 214 may include one or more flow channels 230, which may be coupled to the coolant supply 216, or to a second coolant supply 231 (as depicted in Figure 2).

[0039] In some embodiments, a gas supply 220 may be coupled to the substrate support 208 to supply a backside gas through an opening (shown in Fig. 5) in the support surface 210, which may include a plurality of grooves (not shown) to improve the backside gas circulation. Providing a backside gas can further enhance the rate of cooling of the substrate 212 by improving heat conduction between the substrate and the substrate support 208. For example, Figure 5 depicts a top view of the substrate support in accordance with embodiments of the present disclosure. As illustrated in Figure 5, the substrate support 208 may include a central opening 502 to flow a backside gas to a region disposed between the support surface 210 and a backside of the substrate 212 when disposed on the substrate support 208. The central opening 502 is in fluid communication with the gas supply 220 to flow a backside gas into a space between the support surface 210 and a backside of the substrate 212 to improve the cooling of the substrate.

[0040] Returning to Figure 2, in some embodiments, a controller 250 may be provided for controlling operation of the cooling chamber 200. The controller 250 may be one of any form of general-purpose computer processor that can be used in an industrial setting for controlling various chambers and sub-processors. The memory, or computer-readable medium, 256 of the CPU 252 may be one or more of readily available memory such as random access memory (RAM), read only memory (ROM), floppy disk, hard disk, or any other form of digital storage, local or remote. The support circuits 254 are coupled to the CPU 252 for supporting the processor in a conventional manner. These circuits include cache, power supplies, clock circuits, input/output circuitry and subsystems, and the like.

[0041] The methods disclosed herein may generally be stored in the memory 256 as a software routine 258 that, when executed by the CPU 252, causes the cooling chamber 200 to perform processes of the present disclosure. The software routine 258 may also be stored and/or executed by a second CPU (not shown) that is remotely located from the hardware being controlled by the CPU 252. Some or all of the method of the present disclosure may also be performed in hardware. As such, embodiments of the present disclosure may be implemented in software and executed using a computer system, in hardware as, e.g., an application specific integrated circuit or other type of hardware implementation, or as a combination of software and hardware. The software routine 258 may be executed after the substrate 212 is positioned on the substrate support 208. The software routine 258, when executed by the CPU 252, transforms the general purpose computer into a specific purpose computer (controller) 250 that controls the chamber operation such that the methods disclosed herein are performed.

[0042] Figure 6 depicts a flow diagram illustrating a method 600 in accordance with some embodiments of the present disclosure. The method 600 may be implemented via the controller 250 as discussed above. The method 600 generally begins at 605, where the substrate 212 is placed on the support surface 210 of the substrate support 208. The lift pin assembly 238 extends through the plurality of lift pin holes 504 to receive the substrate 212 and is subsequently lowered to allow the substrate 212 to rest on the support surface (e.g., directly or on the plurality of support elements).

[0043] At 610, the relative position of the substrate support 208 and the plate 214 is moved from a first position (e.g., Figure 2), which facilitates placement and removal of the substrate 212 onto the substrate support 208, to a second position (e.g., Figures 3 and 4), in which the annular seal 236 disposed in the outer ring 232 contacts a periphery of the plate 214 to substantially seal off a second volume 306 from the remaining portion of the inner volume 204 of the cooling chamber 200. In some embodiments, the substrate support 208 is moved and the plate 214 is fixed. In some embodiments, the plate 214 may be moved in addition to or instead of the substrate support 208.

[0044] At 615, a gas is flowed from the gas supply 228 through the central opening 304 of the plate 214 and into the second volume 306. The flow of gas into the second volume 306 increases the pressure inside of the second volume 306 to a pressure higher than that of the inner volume 204. The gas then flows from the second volume 306 through the annular channel 402 and through the at least one through hole 404 into the remaining portion of the inner volume 204. In order to more easily maintain the increased pressure inside of the second volume 306 without raising the pressure within the inner volume 204 by too great an amount, the annular channel 402 and the at least one through hole 404 are sized and shaped to create a choked flow. The increased pressure improves the contact area between the substrate 212 and the support surface 210, which results in improved conduction between the substrate 212 and the support surface 210. Moreover, the increased pressure improves conduction through the gas from the substrate to the plate 214, further enhancing the rate of cooling of the substrate.

[0045] At 620, coolant may be flowed through the one or more flow channels 218 in the substrate support 208, the one or more flow channels 230 in the plate 214, or both, to more rapidly cool the substrate 212. The coolant may include any known coolant such as, for example, water, such as deionized (DI) water, a suitable perfluoropolyether (PFPE) fluid, such as GALDEN®, or the like.

[0046] At 625, the flow of the gas from the gas supply 228 and the gas supply 220 are stopped and the substrate support 208 is moved back to the first position to facilitate removal of the substrate 212 from the substrate support. In the first position, the lift pin assembly 238 extends through the plurality of lift pin holes 504 to lift the substrate 212 off of the support surface 210 to facilitate removal of the substrate 212.

[0047] Although described above with respect to rapid cooling of a substrate in a chamber coupled to a vacuum processing tool, the apparatus as described herein could instead be used for rapid heating of the substrate by providing a heater or flowing a heat transfer fluid at a desired temperature through the flow channels 218, 230.

[0048] While the foregoing is directed to embodiments of the present disclosure, other and further embodiments of the disclosure may be devised without departing from the basic scope thereof.

CLAIMS

1. A cooling chamber for cooling a substrate, comprising:
 - a chamber body having an inner volume;
 - a substrate support disposed in the chamber body and having a support surface to support a substrate;
 - a plate disposed in the chamber body opposite the substrate support, wherein the substrate support and the plate are movable with respect to each other between a first position and a second position, wherein when in the first position the substrate support and the plate are disposed away from each other such that the support surface is exposed to a first volume within the inner volume, wherein when in the second position the substrate support and the plate are disposed adjacent to each other such that the support surface is exposed to a second volume within the inner volume, and wherein the second volume is smaller than the first volume;
 - an annular seal disposed between the substrate support and the plate such that the annular seal contacts the plate when the substrate support and the plate are in the second position;
 - a plurality of flow channels disposed in at least one of the plate or the substrate support to flow a coolant; and
 - a gas inlet to provide a gas into the second volume.
2. The cooling chamber of claim 1, wherein the substrate support comprises an outer ring surrounding the support surface, wherein the outer ring includes an annular groove, and wherein the annular seal is disposed within the annular groove.
3. The cooling chamber of claim 1, wherein the substrate support comprises an outer ring surrounding the support surface, wherein an annular channel is disposed between the outer ring and the support surface extending from the support surface in a direction opposite the plate, and wherein at least one through hole extends from the annular channel to a peripheral surface of the outer ring.

4. The cooling chamber of claim 3, wherein the annular channel is perpendicular to the at least one through hole.
5. The cooling chamber of claim 3, wherein the annular channel and the at least one through hole are shaped and sized to create a choked flow of the gas from the second volume to a remaining portion of the inner volume outside of the second volume.
6. The cooling chamber of claim 1, wherein the plurality of flow channels are disposed in the plate.
7. The cooling chamber of claim 1, wherein a substrate support facing surface of the plate is concave.
8. The cooling chamber of claim 1, wherein the substrate support comprises a plurality of support elements disposed on the support surface to support a substrate in a spaced apart relation to the support surface.
9. The cooling chamber of claim 1, wherein the substrate support comprises an opening to flow a backside gas between a substrate and the support surface when the substrate disposed on the substrate support.
10. The cooling chamber of claim 1, wherein the substrate support comprises a lift pin assembly to facilitate placement and removal of a substrate onto and off of the substrate support.
11. The cooling chamber of claim 1, wherein the gas inlet is disposed through the plate.
12. A substrate processing system, comprising:
a central vacuum transfer chamber;

at least one vacuum processing chamber coupled to the central vacuum transfer chamber to perform a process on a substrate; and

a cooling chamber coupled to the central vacuum transfer chamber to cool the substrate, the cooling chamber comprising:

a chamber body having an inner volume;

a substrate support disposed in the chamber body and having a support surface to support a substrate;

a plate disposed in the chamber body opposite the substrate support, wherein the substrate support and the plate are movable with respect to each other between a first position and a second position, wherein when in the first position the substrate support and the plate are disposed away from each other such that the support surface is exposed to a first volume within the inner volume, wherein when in the second position the substrate support and the plate are disposed adjacent to each other such that the support surface is exposed to a second volume within the inner volume, and wherein the second volume is smaller than the first volume;

an annular seal disposed between the substrate support and the plate such that the annular seal contacts the plate when the substrate support and the plate are in the second position;

a plurality of flow channels disposed in at least one of the plate or the substrate support to flow a coolant; and

a gas inlet to provide a gas into the second volume.

13. A cooling chamber for cooling a substrate, comprising:

a chamber body having an inner volume;

a substrate support disposed in the chamber body and having a support surface to support a substrate;

a plate disposed in the chamber body opposite the substrate support, wherein the substrate support and the plate are movable with respect to each other between a first position and a second position, wherein when in the first position the substrate support and the plate are disposed away from each other within the inner volume,

wherein when in the second position the substrate support and the plate are disposed adjacent to each other and together at least partially define a second volume that is smaller than and substantially sealed off from a remaining portion of the inner volume, and wherein the support surface is exposed to the second volume;

a plurality of flow channels disposed in at least one of the plate or the substrate support to flow a coolant; and

a gas inlet to provide a gas into the second volume.

14. The cooling chamber of claim 13, further comprising:

an annular seal disposed between the substrate support and the plate to substantially seal off the second volume from the remaining portion of the inner volume when in the substrate support and the plate are in the second position.

15. The cooling chamber of claim 13, further comprising:

an outer ring surrounding the support surface and including at least one through hole fluidly coupling the second volume to the remaining portion of the inner volume to control the flow of gas from the second volume into the remaining portion of the inner volume.